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JUN 15 2006

PATENT
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the **PATENT APPLICATION** of:

Ching-Wei Lin

Application No.: 10/767,665

Confirmation No.: 5412

Filed: January 29, 2004

For: PROCESS FOR FORMING
POLYCRYSTALLINE SILICON LAYER BY
LASER CRYSTALLIZATION

Group: 2813

Examiner: Stephen W. Smoot

Our File: TET-PT049

Date: June 15, 2006

RESPONSE TO NON-COMPLIANT
AMENDMENT PURSUANT TO 37 C.F.R. 1.121

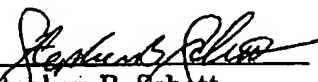
Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Enclosed is the signed amendment.

Respectfully submitted,

Ching-Wei Lin

By 
Stephen B. Schott
Registration No. 51,294
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Volpe and Koenig, P.C.
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